Publikationen

(2013): Scanning probe microscopy based electrical characterization of thin dielectric and organic semiconductor films. In: 24th European Symposium on Reliability of Electron Devices, Failure Physics and Analysis (ESREF), Arcachon, Frankreich.

(2013): Scanning probe microscopy based electrical characterization of thin dielectric and organic semiconductor films. In: Microelectronics Reliability, vol. 53, no. 9-11, pp. 1430-1433.

(2013): Analysis of crystal defects on GaN based semiconductors with advanced scanning probe microscope technique. In: Thin Solid Films, vol. 544, no. Oktober, pp. 139-143.

(2012): Analysis of crystal defects on GaN-based semiconductors with advanced scanning probe microscope techniques. Invited Talk. In: 6th International Conference on Technological Advances of Thin Films & Surface Coatings (THINFILMS2012), Singapur, Singapur.

(2011): Capacitance and Conductivity Mapping of Organic Films and Devices with Non-Contact SPM Methods. In: International Workshop on Scanning Probe Microscopy for Energy Applications, Mainz.

(2010): Intermittent-Contact Capacitance Spectroscopy – A new method for determining C(V) curves with sub-micron lateral resolution. In: Microelectronics Reliability, vol. 50, pp. 1511-1513.

(2010): Displacement Current Sensor for two-dimensional dopant profiling. In: ITG Discussion, Grainau.

(2010): Intermittent-Contact Scanning Capacitance Analysis of Thin Dielectric Films and Semiconductor Devices. Invited Talk. In: 5th International Conference on Technological Advances of Thin Films & Surface Coatings, Harbin, China.

(2009): A Review of Advanced Scanning Probe Microscope Analysis of Functional Films and Semiconductor Devices. In: Thin Solid Films, vol. 517, no. 17, pp. 5100-5105.

(2009): Displacement current sensor for contact and intermittent contact scanning capacitance microscopy. In: Microelectronics Reliability, vol. 49, no. 1, pp. 1192-1195.

(2008): A Review of Advanced Scanning Probe Microscope Analysis of Functional Films and Semiconductor Devices. Invited Talk. In: Thin Films, Singapur.

(2008): Dopant profiling with Intermittent-Contact Scanning Capacitance Microscopy. In: ITG Discussion, Grainau.

(2008): Intermittent-contact scanning capacitance microscopy versus contact mode SCM applied to 2D dopant profiling. In: Microelectronics Reliability, vol. 48 (8-9), pp. 1339-1349.